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MEMC 98-3052 (2512.2)
PATENT

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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application of Robert J. Falster

Art Unit 2814

Serial No. 10/038,084

Filed January 03, 2002

Confirmation No. 7363

For SILICON ON INSULATOR STRUCTURE HAVING A LOW DEFECT DENSITY
DEVICE LAYER AND A PROCESS FOR THE PREPARATION THEREOF

Examiner Anh D. Mai

April 17, 2003

RESPONSE TO RESTRICTION REQUIREMENT

TO THE ASSISTANT COMMISSIONER FOR PATENTS,

SIR:

In response to the restriction requirement dated March 6, 2003, Applicant elects examination of claims 47-51 (Group II).

Applicant therefore withdraws from consideration, without prejudice to their patentability, claims 4-46 (Group I). Applicant also expressly reserves the right to file one or more divisional applications directed to these claims in the future.

Respectfully submitted,

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